



**SECOND SEMESTER 2020 - 2021**

Course Handout Part II

16.1.2021

In addition to Part I (general Handout for all courses appended to the Time Table), this portion gives further specific details regarding the course.

Course No. : PHY F379  
Course Title : Thin film technology  
Instructors : **Dr. V. Satya Narayan Murthy** & Prof. Harihara Venkataraman

**Course Description:** This course gives an overview of thin film technology - Basics of vacuum science and technology, Thin film deposition techniques; Kinetics and diffusion mechanisms, Surface nucleation and film growth, Structure and morphology of thin films, Electrical and magnetic properties, Special topics on thin film application.

**Scope & Objective:**

- The course introduces the concepts in vacuum deposition techniques, nucleation and growth of thin films.
- Techniques to characterize the thin films and some of the physical properties of films and their applications.

**Text Book:** No single textbook exists. Lecture notes will be distributed.

**Reference Books:**

- Materials Science of Thin Films – Milton Ohring, 2<sup>nd</sup> Edition (Elsevier)
- A User's Guide to Vacuum Technology - J.F. O' Hanlan
- Thin film deposition principles and practice – Smith Donald
- Thin Film Phenomena – Kasturi L Chopra (McGraw - Hill)

**Course Plan:**

<b>Lecture No.</b>	<b>Learning Objectives</b>	<b>Topics to be covered</b>	<b>Chapter in the Text Book</b>
1 - 6	Vacuum technology	Mean free path, gas flow regimes, conductance, pumping speed, vacuum levels, working principles of different vacuum pumps, vacuum gauges, vacuum leak detection,	Lecture notes + relevant portions



		vacuum seals	from reference books
7 - 10	Thin film deposition	Differences between CVD and PVD, different PVD techniques – thermal and electron beam evaporation, sputtering, PLD, MBE, etc., evaporation rate, evaporation of multielement materials and alloys	
11 - 14	Film thickness uniformity and purity	Thickness measurement techniques, deposition geometry, thickness uniformity	
15 - 21	Nucleation and growth of thin film	Thermodynamic aspects of nucleation and growth – capillarity theory of heterogeneous nucleation, atomistic theory, growth modes	
22 - 29	Characterization techniques	Structural techniques (XRD), imaging techniques (SEM / TEM), optical techniques, chemical techniques	
30 - 35	Properties of thin films	Electrical, dielectric, ferroelectric and magnetic properties	
36 - 42	Applications	Sensors, solar cells, giant magnetoresistance, ferroelectric effect, multiferroics	

### Evaluation Scheme:

EC No .	Evaluation Scheme	Duration	Weightage (%)	Date & Time	Nature of Component
1.	Midsem Examination	90 min.	35	01/03 11.00 -12.30PM	Open Book
2.	2 Quizzes		25		Open Book
3.	Comprehensive Examination	120 min.	40	01/05 AN	Open Book

**Notices:** Notices for the course will be displayed on **Physics** notice board.

**Make-up Policy:** Make up will be given strictly to **genuine cases only** i.e. (i) Sickness leading to hospitalization, (ii) Out of station with prior intimation & permission.

**No make-up for Quiz.**

**Academic Honesty and Integrity Policy:** Academic honesty and integrity are to be maintained by all the students throughout the semester and no type of academic dishonesty is acceptable.



Instructor-in-Charge

PHY F379

